

APPLICATION DATA SHEET

APPLICATION INFORMATION

Application Number::	
Filing Date::	May 18, 2006
Application type::	Regular
Subject Matter::	Utility
Title::	Plasma Film-Forming Apparatus and Plasma Film-Forming Method
Attorney Docket No.::	101994.57726US
Request for Early Publication?::	No
Request for Non-Publication?::	No
Suggested Drawing Figure::	1
Total Drawing Sheets::	10
Small Entity?::	No
Petition included?::	No



APPLICANT INFORMATION

Applicant one Authority Type::	Inventor
Primary Citizenship Country::	JAPAN
Status::	Full Capacity
Given name::	Hiraku
Family name::	ISHIKAWA
City of Residence::	Amagasaki-shi
State or Province of Residence::	Hyogo
Country of Residence::	Japan
Street of mailing address::	c/o Intellectual Property Dept. Tokyo Electron Limited 3-6, Akasaka 5-chome
City of mailing address::	Minato-ku
State or Province of mailing address::	Tokyo
Country of mailing address::	Japan
Postal or Zip Code of mailing address::	107-8481

CORRESPONDENCE INFORMATION

Correspondence customer number:: 23911

REPRESENTATIVE INFORMATION

Representative customer number:: 23911

DOMESTIC PRIORITY INFORMATION

Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This application is a	National Stage of	PCT/JP2004/017162	11/18/2004

FOREIGN PRIORITY INFORMATION

Country::	Application Number::	Filing Date::	Priority Claimed::
JAPAN	2003-389469	11/19/2003	Yes

ASSIGNEE INFORMATION

Assignee Name:: TOKYO ELECTRON LIMITED
Street of mailing address:: 3-6, Akasaka 5-chome
City of mailing address:: Minato-ku
State or Province of Mailing Address:: Tokyo
Country of Mailing Address:: Japan
Postal or Zip Code of mailing address:: 107-8481